

In the Specification

The amendments to the following paragraphs are shown below.

Please replace the paragraph at page 1, line 23 to line 27 with the following paragraph:

One tool that is sometimes used to measure diffracting structures is a scatterometer.

Scatterometry is an angle-resolved measurement and characterization of light scattered from a structure. Scatterometry is discussed in detail in U.S. Serial No. 09/036,557, filed March 6, 1998, now US 6,483,580 B1, which is assigned to KLA-Tencor Corporation, which has an International Publication No. WO 99/45340, dated September 10, 1999, and which is incorporated herein by reference.

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